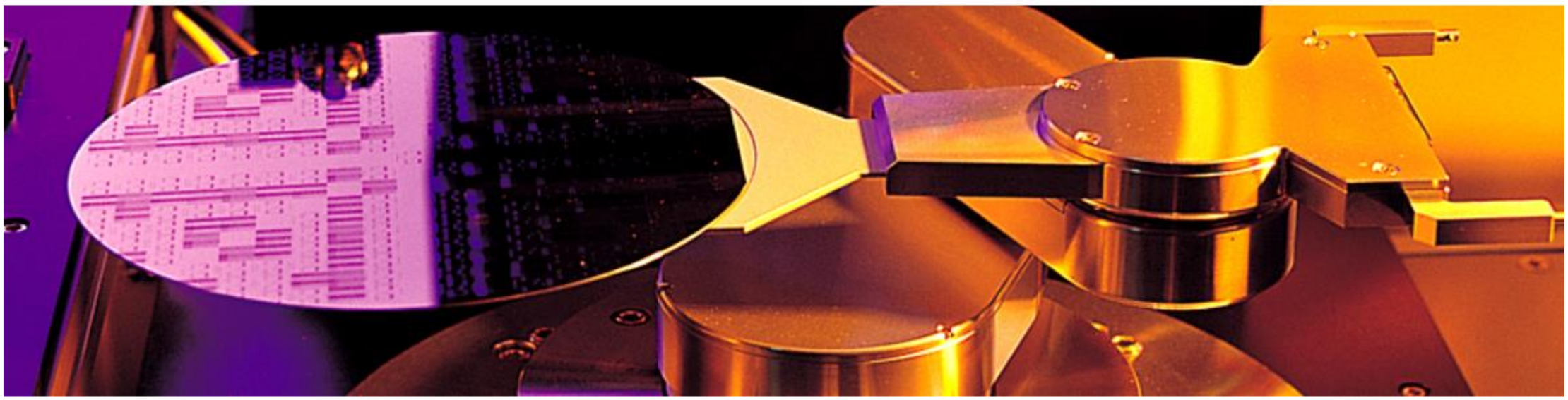
MOOV

MIDAS

MIDAS SYSTEM



# Mask Aligner

# MDA-600S

## ■ 150mm Semi-automatic Mask Aligner




## FEATURE

- Piece ~ 6 inch(150mm) wafer
- Semi-automatic control system
- PC(Window10)& PLC controller
- Z-axis stage motorized
- Beam size: 6.25” x 6.25”
- Alignment accuracy: 1um
- 350W lamp(Option: 500W)
- 350W Power supply
- Anti –Vibration Frame

# MDA-600S

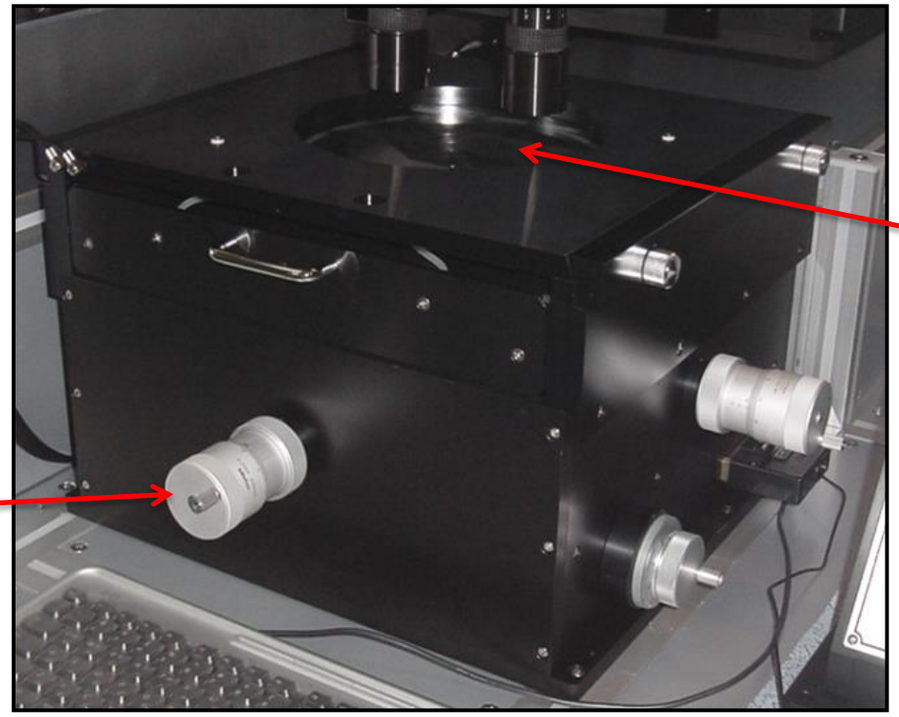
| | Item | Specification |
|---|---|---|
| Exposure System | Lamp Power | 350W |
| | Resolution | 0.8um |
| | Beam Uniformity | ≤ 3.0% (6”) |
| | Beam Intensity | 20-30mW/cm$^{2,}$ |
| | Adjustable Exposure | 0.1 to 999.9 sec |
| Alignment System | Alignment Accuracy | 1.0um |
| | BSA accuracy | 1.5um |
| | Control type | PC(Window10) & PLC control |
| | Process Mode | Vacuum, Hard, Soft Contact |
| | | Proximity |
| | Proximity Adjustment | adjustable 1 micron increments |
| | Wavelength | 350nm~450nm |
| Sample | Substrate | up to 6 inch |
| | Mask Size | up to 7 × 7 inch |
| Utilities | Vacuum | > 650mmHg |
| | CDA | > 6Kg/cm$^2$ |
| | $N_2$ | > 4Kg/cm$^2$ |
| | Electricity | 220V, 15A, 1Phase |

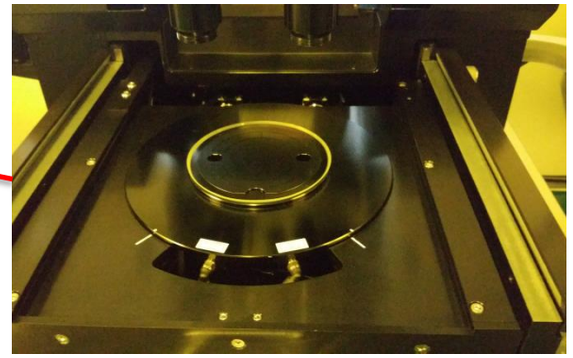
# MDA-600S

## ● Stage module



Stage Y-axis micrometer

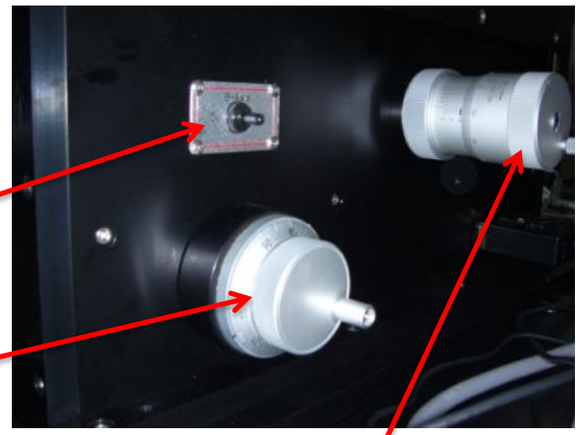




CHUCK

Stage Θ-axis high speed micrometer

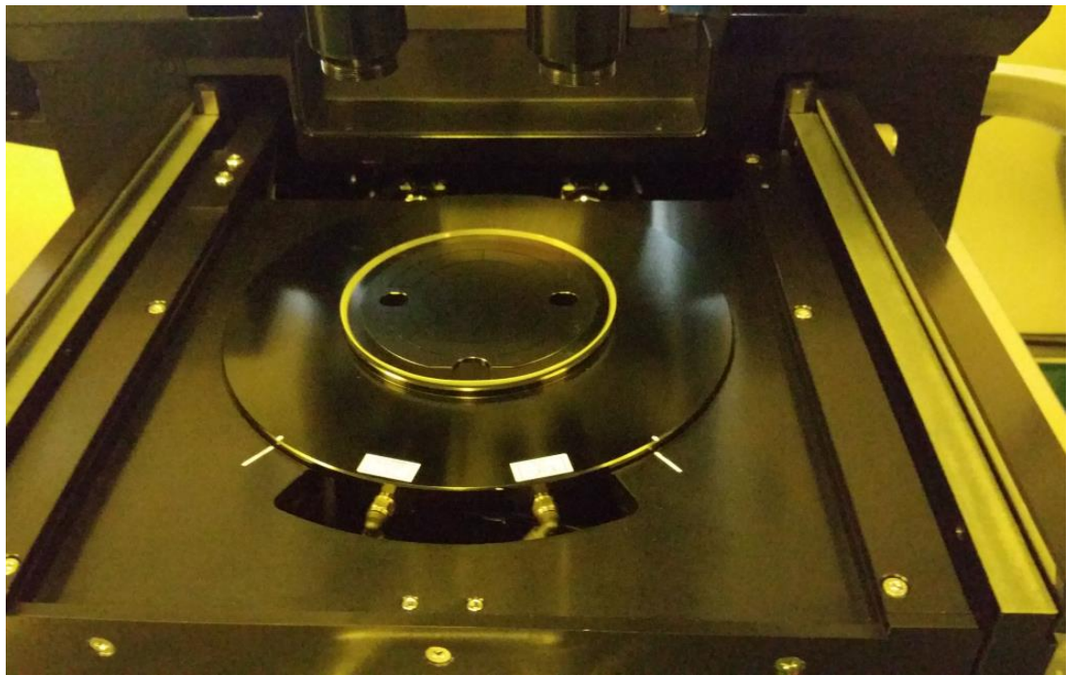
Stage Θ-axis low speed micrometer



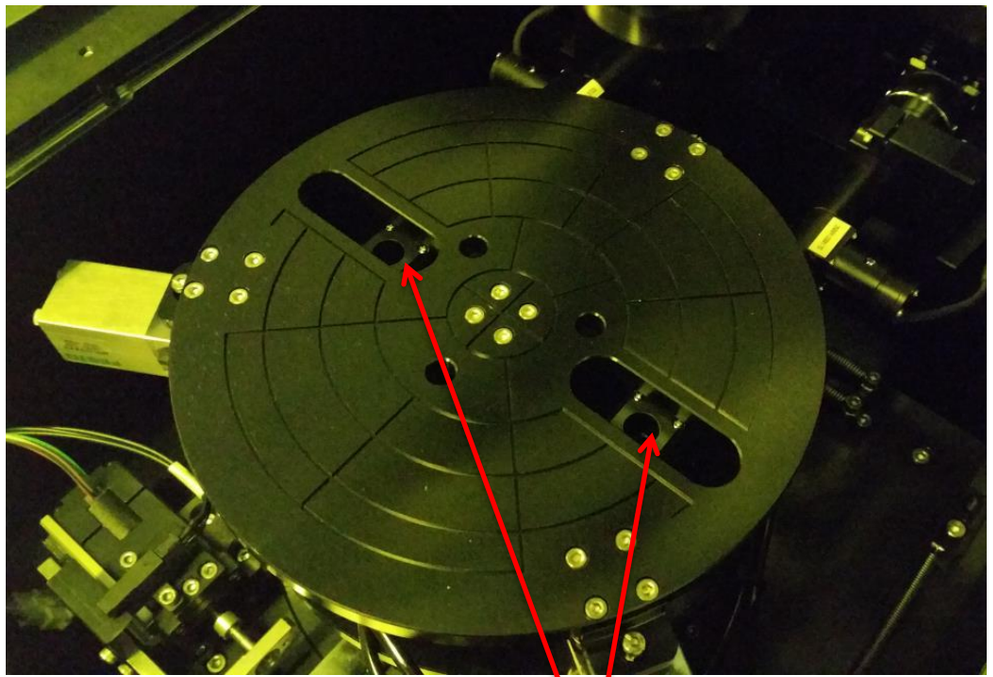
Stage X-axis micrometer

# MDA-600S

## ● Stage & Chuck module



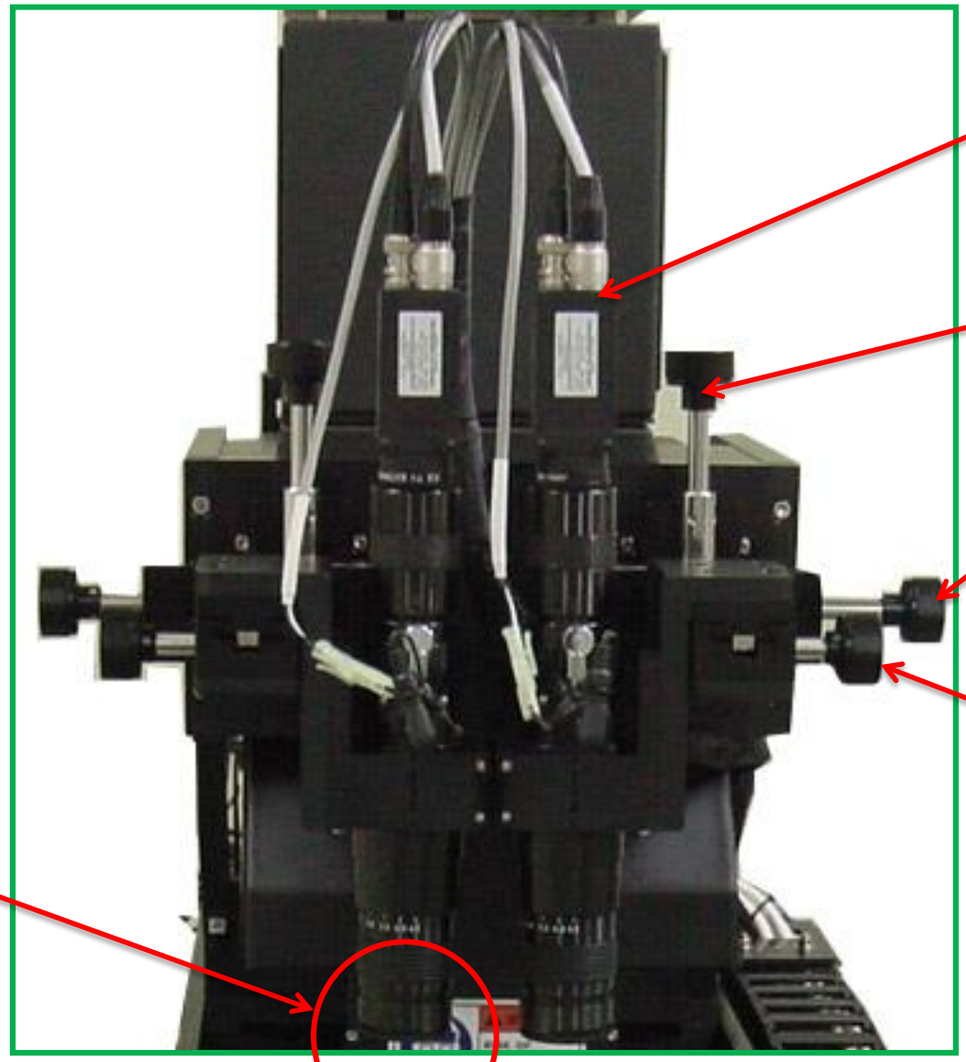
Chuck module

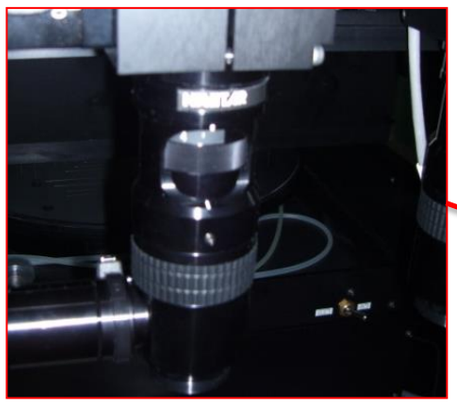


BSA(Back-side camera) module

# MDA-600S

## ● Microscope module

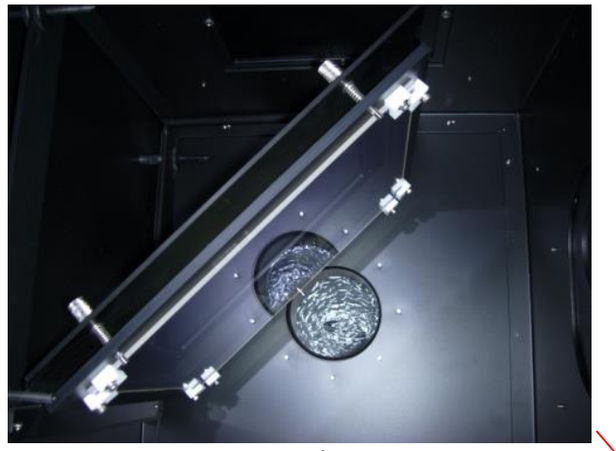


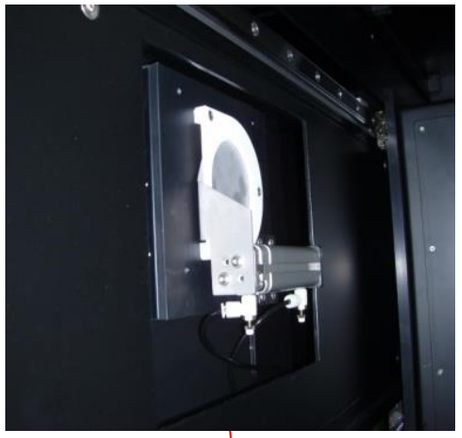



Focus

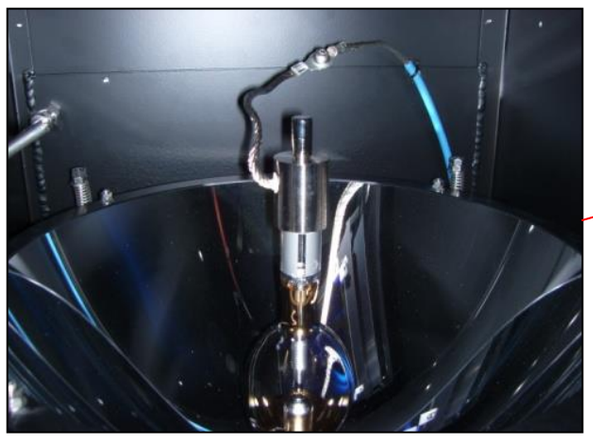
# MDA-600S

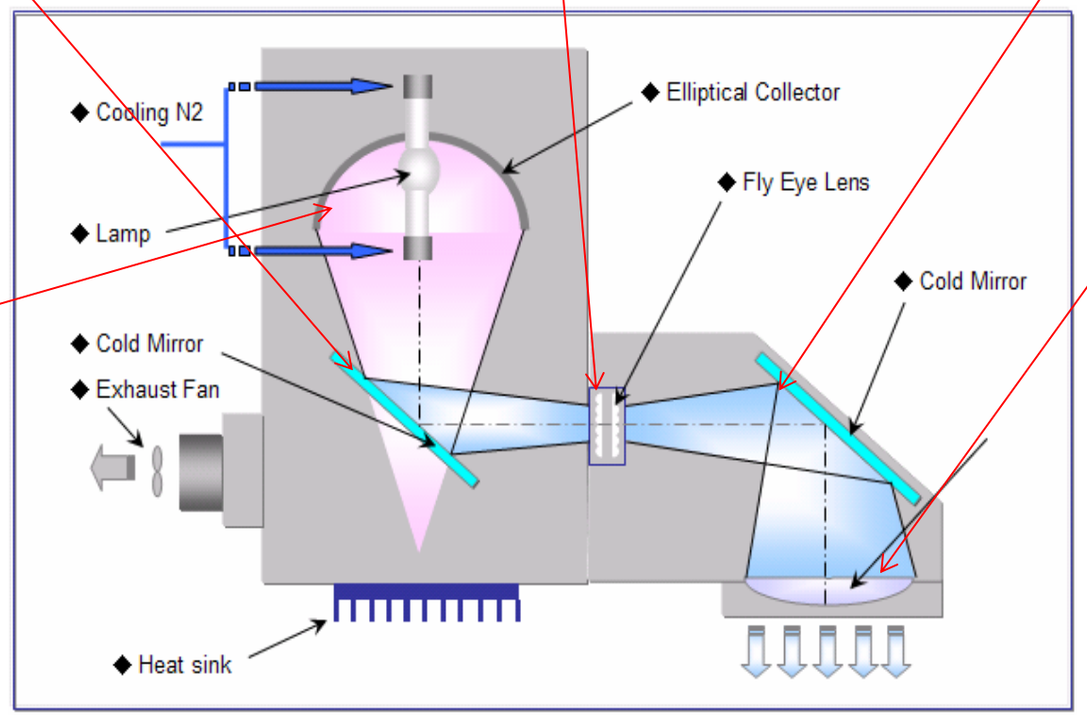
## ● Exposure module

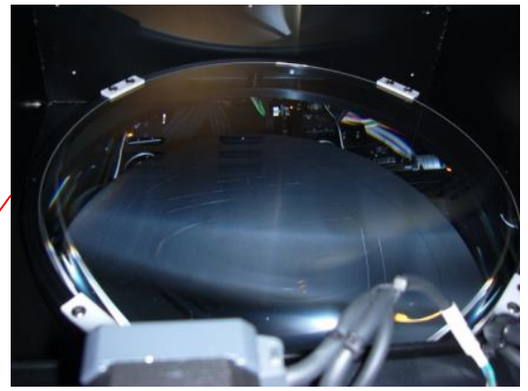


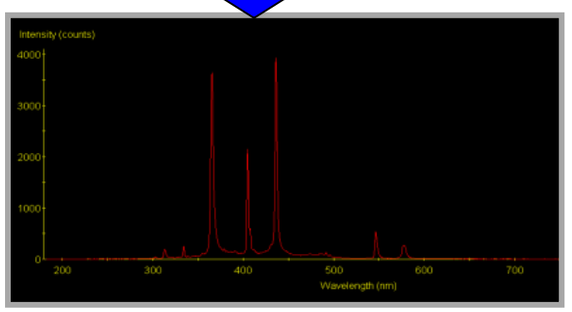










# MDA-600S

## ● Process SEM Images

